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1 High-efficiency and low-loss gallium nitride dielectric metasurfaces 2 for nanophotonics at visible wavelengths

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15 The dielectric nanophotonics research community is currently exploring transparent material
16 platforms (e.g., TiO₂, Si₃N₄, and GaP) to realize compact high efficiency optical devices at visible
17 wavelengths. Efficient visible-light operation is key to integrating atomic quantum systems for
18 future quantum computing. Gallium nitride (GaN), a III-V semiconductor which is highly transpar-
19 ent at visible wavelengths, is a promising material choice for active, nonlinear, and quantum nano-
20 photonic applications. Here, we present the design and experimental realization of high efficiency
21 beam deflecting and polarization beam splitting metasurfaces consisting of GaN nanostructures
22 etched on the GaN epitaxial substrate itself. We demonstrate a polarization insensitive beam
23 deflecting metasurface with 64% and 90% absolute and relative efficiencies. Further, a polarization
24 beam splitter with an extinction ratio of 8.6/1 (6.2/1) and a transmission of 73% (67%) for
25 p-polarization (s-polarization) is implemented to demonstrate the broad functionality that can be
26 realized on this platform. The metasurfaces in our work exhibit a broadband response in the blue
27 wavelength range of 430–470 nm. This nanophotonic platform of GaN shows the way to off- and
28 on-chip nonlinear and quantum photonic devices working efficiently at blue emission wavelengths
29 common to many atomic quantum emitters such as Ca⁺ and Sr⁺ ions. *Published by AIP Publishing.*
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30 Metasurfaces have emerged as a highly promising
31 approach to realize compact nanophotonic devices including
32 phase masks,¹ waveplates,² focusing lenses,³ focal plane
33 arrays,⁴ flat mirrors,⁵ and holograms.⁶ Most of the early
34 studies on metasurfaces were based on thin plasmonic nano-
35 antenna arrays arranged in various permutations and combi-
36 nations.^{7,8} Plasmonic metasurfaces enable light manipulation
37 with ultrathin devices, but they suffer significant ohmic
38 losses which degrade the performance of all plasmonic devi-
39 ces. This is fundamentally due to the fact that the electro-
40 magnetic energy is stored as kinetic energy of electrons for
41 one-half of the optical cycle.⁹ On the other hand, in the past
42 couple of years, dielectric metasurfaces have gained increas-
43 ing prominence essentially because of the small optical loss
44 in dielectrics at frequencies below their bandgaps as well as
45 the capability of high index dielectric materials to support
46 both electric and magnetic resonances in nanostructures,
47 which offers a richer design space.¹⁰ To date, the dielectric
48 metasurface research community has predominantly focused
49 on developing the design concepts based on resonant anten-
50 nas,^{10,11} Pancharatnam-Berry phase,^{12–15} and waveguide

51 approaches^{16–19} to improve the efficiency of nanophotonic
52 devices. Interestingly, the use of high index dielectrics to
53 design subwavelength gratings has been investigated almost
54 two decades earlier. We refer to an excellent recent review
55 by Lalanne and Chavel for a comprehensive historical back-
56 ground on the dielectric approach to metalenses.²⁰

57 A survey of the dielectric metasurface literature also
58 reveals that silicon, more specifically amorphous Si, has
59 been extensively used primarily because of its well-
60 established nanofabrication processes. However, Si is not a
61 good material choice at visible wavelengths because of its
62 strong intrinsic absorption. Wide bandgap dielectrics such as
63 TiO₂^{15,17,21} and Si₃N₄,²² which are transparent at visible
64 wavelengths, are currently being investigated as potential
65 low-loss alternatives. The materials discussed thus far are all
66 passive and hence are not suitable for active applications
67 where optical gain is necessary. Direct bandgap III-V materi-
68 als are very promising for such active applications because
69 of their strong dipole transition strength and smaller free
70 carrier lifetimes compared to indirect bandgap materials.
71 Typically, the crystal structure of III-V materials does not
72 possess centrosymmetry, and hence, they exhibit large sec-
73 ond order susceptibility ($\chi^{(2)}$), which can be exploited to real-
74 ize optically switchable nonlinear devices. Indeed, recently,
75 GaAs-based high aspect ratio nanostructures have been used

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76 to demonstrate optical switching of metasurfaces.^{23–25} Even
 77 though GaAs is a good material choice for both nonlinear
 78 response and emission at near-IR wavelengths, it cannot be
 79 applied at visible wavelengths due to its high optical losses.
 80 Another potential alternative is GaP, which was shown to be
 81 an effectively loss-less platform for dielectric metasurfaces
 82 above 560 nm.²⁶ Efficient blue wavelength operation is of
 83 critical importance for on-chip quantum and nonlinear optics
 84 with color-centers and atomic transitions.²⁷ In this paper, we
 85 experimentally demonstrate epitaxial GaN on sapphire, which
 86 is a material of immense technological interest for solid-state
 87 lighting technologies, as a viable platform for metasurfaces at
 88 visible wavelengths. Thanks to its high transparency through
 89 the whole visible spectrum, relatively high refractive index
 90 (>2.4 in the visible), and well-developed industrial use as an
 91 active material for blue-, cyan-, and green-emitting LEDs and
 92 lasers for general lighting, backlighting, and other applica-
 93 tions, this platform may pave the way for applications of
 94 dielectric metasurfaces to nonlinear and quantum optics.
 95 Indeed, III-Nitride materials have already been used to dem-
 96 onstrate electrically driven,²⁸ room-temperature²⁹ single pho-
 97 ton emission. Here, we experimentally show a high-efficiency
 98 beam deflecting metasurface and a polarization-splitting
 99 metasurface as examples of the viability of GaN as a platform
 100 for nanophotonics. The metasurfaces were realized on top of
 101 epitaxial GaN on sapphire wafer by etching the nanostructures
 102 directly into the epitaxial GaN layer. Very recently, first
 103 demonstrations of GaN based focusing lenses with a transmis-
 104 sivity of $\sim 86\%$ for blue wavelength operation have been pub-
 105 lished.^{30,31} In these examples, GaN nanostructures were
 106 fabricated directly on top of a sapphire substrate. In our work,
 107 GaN nanoantennas are located on the GaN epitaxy with the
 108 same refractive index, which paves the way for a wider range
 109 of applications but provides additional design constraints.

110 The primary building block of our metasurface, opti-
 111 mized for operation at a wavelength of 460 nm, which is a typ-
 112 ical emission peak for digital lighting and backlighting,³² is a
 113 nanopillar of height 460 nm, as schematically illustrated in

114 Fig. 1(a). Each pillar can be considered as a waveguide which
 115 allows certain modes to propagate with an effective mode
 116 index defined by the pillar diameter. The phase shift and trans-
 117 mission through the unit cell, which are dependent on the
 118 diameter and the height of the nanopillar, were calculated by
 119 numerical modeling using the finite difference time domain
 120 (FDTD) technique in commercially available LumericalTM
 121 software. The relative phase accumulated along the nanopillar,
 122 with the size of unit cell fixed at 330 nm in both lateral dimen-
 123 sions and 460 nm in height, can be seen in Fig. 1(b). The
 124 period of the repeating nanopillars was chosen such that the
 125 resulting nanopillar array is sub-diffractive (in air) and small
 126 enough to achieve sufficient phase sampling while being also
 127 large enough to neglect interactions between nanopillars. To
 128 verify the hypothesis of non-interacting nanopillars, we calcu-
 129 lated the phase delay introduced by 460 nm length of an iso-
 130 lated long cylinder given by $460 \text{ nm} \times \beta_{HE11}$, where β_{HE11}
 131 is the propagation constant of the fundamental mode in a long
 132 cylinder.³³ This is shown as a dashed line in Fig. 1(b), which
 133 closely follows the phase delay estimated by the FDTD simu-
 134 lations, indicating that the phase shift introduced by the nano-
 135 pillar is a local phenomenon, and hence, the mode is strongly
 136 confined within the nanopillar. Using the nanopillars with
 137 diameters tuned from 80 to 210 nm, we are able to achieve a
 138 full phase coverage of 2π , enabling complete wavefront con-
 139 trol, while simultaneously maintaining high optical transmis-
 140 sion ($>70\%$).

141 To realize a metasurface capable of beam deflection, we
 142 introduce a super-cell in the x -direction by choosing nanopil-
 143 lars of diameters 124 nm, 143 nm, 167 nm, and 207 nm, which
 144 introduce respective phase shifts of approximately $\frac{\pi}{2}$, π , $\frac{3\pi}{2}$,
 145 and 2π [marked by green solid circles in Fig. 1(b)]. This
 146 supercell introduces a linear phase gradient in the x -direction
 147 with a periodicity of 1320 nm. In the y -direction, the metasur-
 148 face is sub-diffractive with a unit cell period of 330 nm. The
 149 designed phase gradient will cause the metasurface to deflect
 150 a plane wave incident from the substrate into the T_{+1} diffrac-
 151 tive order. In principle, if the phase sampling is continuous

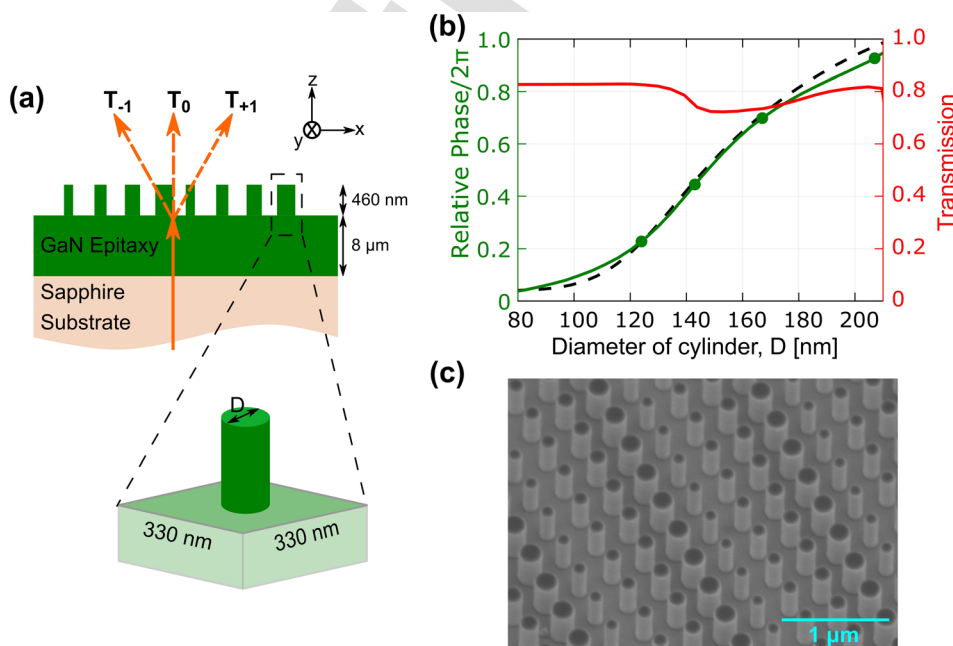


FIG. 1. (a) Schematic illustration of the proposed metasurface capable of deflecting the incident beam from the substrate into the T_{+1} direction. The substrate dimensions, height, and sizes of designed nanopillars are as shown. The diameter D was varied from 80 to 210 nm to realize a linear phase gradient between 0 and 2π . (b) Numerical calculations of the relative phase shift introduced by the nanopillars and transmission for a plane wave with 460 nm wavelength, incident from the substrate side. The dashed black curve is the analytical calculation of the phase shift introduced by an isolated cylinder. (c) SEM image of the fabricated GaN sample.

152 and the transmission is constant, it is possible to achieve
153 100% deflection efficiency^{34,35}—meaning that there is negli-
154 gible power in T_0 and T_{-1} orders at the operating wavelength.

155 However, the 4-level discretization, which we chose to
156 use here, limits the theoretical absolute efficiency of beam
157 deflection into the first order to $\sim 81\%$.³⁶ We should also
158 note that in our present system, since the metasurface is of
159 the same material as the underlying epitaxial substrate, the
160 resulting diffraction into the substrate cannot be avoided.
161 This can be expected to result in a further reduction in the
162 diffraction efficiency.

163 The sample as described above was fabricated using stan-
164 dard e-beam lithography and inductively coupled reactive ion
165 etching processes (see [supplementary material A1](#) for addi-
166 tional details). A representative scanning electron microscopy
167 (SEM) image of the metasurface studied in this work is shown
168 in Fig. 1(c). The sample was characterized by illuminating it
169 using a halogen lamp under normal incidence through the sub-
170 strate and collecting the back-focal plane image (with an input
171 slit) using a CCD camera (see [supplementary material A2](#) for
172 additional details). The images captured on the CCD show
173 spectral and k -dependence of the energy distribution in vari-
174 ous diffractive orders.^{37,38} The results for the p -polarization
175 (electric field along the long period of the super-cell) are
176 shown in Fig. 2(a). The white dashed lines represent the
177 expected diffraction orders (in air) for our design. Clearly,
178 most of the incident light is deflected into the T_{+1} order with
179 the deflection angle dependent on the operating wavelength as
180 expected from a diffractive design. Figure 2(b) shows the
181 measured diffraction intensity normalized to the transmitted
182 intensity through the substrate. These curves are obtained by
183 averaging five image pixels on either side of the diffraction
184 orders depicted as white dashed lines in Fig. 2(a) (the number

of pixels is selected to fully integrate the energy going into
each individual diffraction order at the image). The corre-
sponding FDTD simulations are shown as dashed curves. Figure 2(c) shows the relative efficiency, which is defined as the ratio of intensity in the desired diffraction order to the total transmitted intensity, reaching about 90% at the design wavelength of 460 nm where the deflection angle is 20° . The corresponding measured and simulated data for the s -polarization (electric field perpendicular to the long period of the supercell) are shown in Figs. 2(d)–2(f). The experimental measurements correspond closely to the simulations and show a peak transmission efficiency of $\sim 70\%$ for both the s - and p -polarizations. The transmission into the T_0 and T_{-1} orders is quite small and is limited to about 6% and 1%, respectively. The polarization insensitive behavior of our device is not surprising given the circular cross-section of the nanopillar design. The main features predicted by the numerical simulations are well reproduced in the experiment. Small discrepancies related to the absence in experiment of sharp spectral features predicted by simulations around 440 nm can be attributed to unavoidable nanofabrication imperfections in sidewall profiles and corner rounding, which are different for nanopillars of varying dimensions.

To show the versatility of the proposed GaN platform, we now demonstrate a metasurface with the polarization beam splitting functionality. A polarization selective metasurface can be realized by replacing the circular nanopillar by an elliptical nanopillar, wherein the phase velocity of the mode is dependent on the orientation of the input polarization with respect to the major axis of the ellipse. Here, we design and experimentally show a polarization beam splitting metasurface that deflects the p -polarized incoming light into the T_{+1} diffractive order and the s -polarization into the

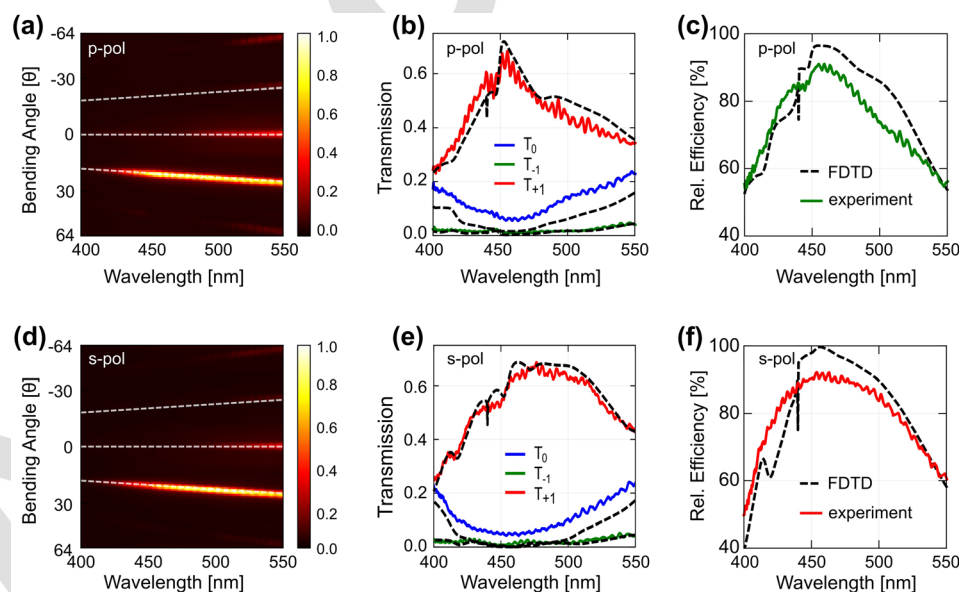


FIG. 2. Measured energy distribution into different diffraction orders as a function of the wavelength for a beam deflecting metasurface illuminated by the p -polarized (a), (b), and (c) and s -polarized (d), (e), and (f) light through the substrate. The transmitted light is predominantly bent into the T_{+1} order, with negligible intensity in the T_0 and T_{-1} orders at the operating wavelength of 460 nm. The white dashed lines in (a) and (d) represent the diffraction orders into air calculated for the supercell period of 1320 nm. The color bar in (a) and (d) represents the transmitted intensity normalized to incident light at each wavelength. The experimental data (b) and (e) are obtained by averaging five pixels on either side of the diffracted orders (the white dashed lines) normalized to the substrate transmission (the number of pixels is selected to fully integrate the energy going into each individual diffraction order at the image). The black dashed curves are the simulated results, which closely match the experimental trends. Relative efficiency (c) and (f), defined as the transmitted intensity into the desired diffraction order normalized to the total transmitted intensity, reaches the level of $\sim 90\%$ at the operation wavelength.

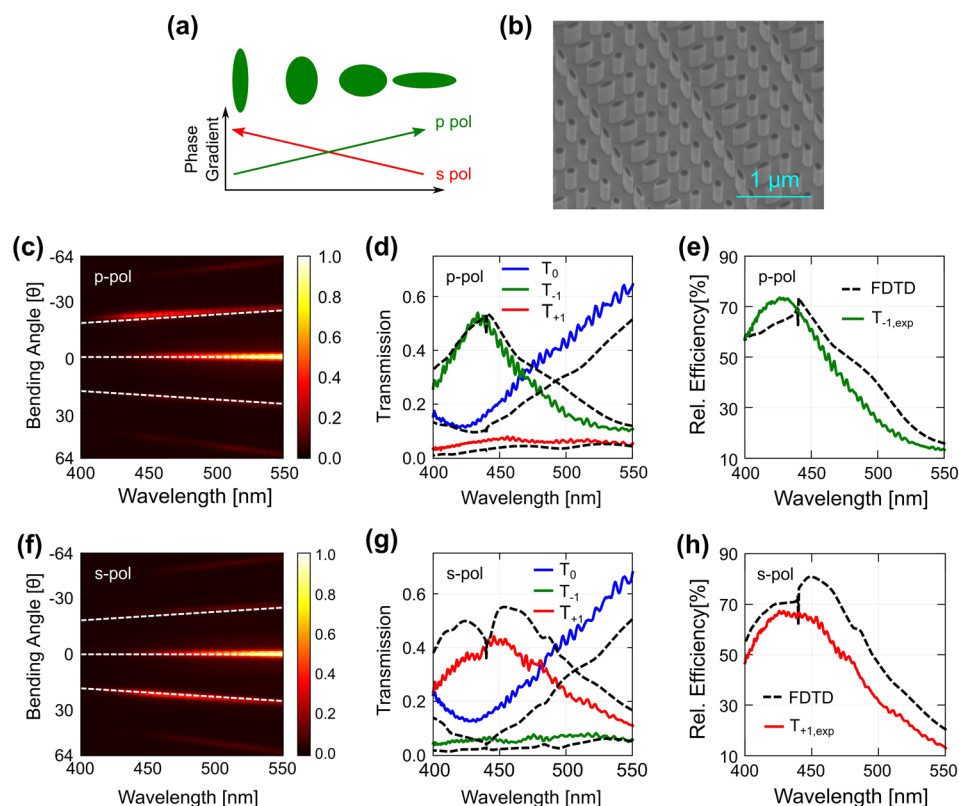


FIG. 3. (a) Schematic illustration of the phase gradients employed to demonstrate polarization beam splitting metasurface. The phase introduced by each nanopillar is dependent on the radii and the orientation relative to the polarization direction. (b) A representative SEM image of the fabricated GaN device. (c) and (f) Spectrally resolved back focal plane images showing the intensity of light transmitted in various diffraction orders for the p - and s -polarizations, respectively. For the p -polarized illumination, the transmitted light deflects predominantly into the T_{-1} diffraction order, while for the s -polarized illumination, the light is directed into the T_{+1} order. (d) and (g) Spectral dependence of intensity in the T_{-1} , T_0 , and T_{+1} diffraction orders for the p - and s -polarizations, respectively. (e) and (h) Relative efficiencies of light channeling into the T_{+1} and T_{-1} orders, for the p - and s -polarizations, respectively. The measured peak relative efficiencies of beam deflection are 73% for the p -polarization and 67% for the s -polarization at 430 nm illumination. The solid colored curves represent the measured values, while the black dashed ones correspond to the numerical simulations.

218 T_{-1} diffractive order. The design principles are similar to the
 219 phase gradient concepts discussed earlier with one major dif-
 220 ference—the ellipses in the supercell are arranged such that
 221 the phase gradients point in opposite directions for the p - and
 222 s -polarizations, as schematically shown in Fig. 3(a). The
 223 amplitude transmission coefficient and phase maps obtained
 224 by varying the radii of elliptical nanopillars and the specific
 225 design parameters used are given in the [supplementary mate-](#)
 226 [rial](#) (A3). The design height was kept fixed at 460 nm similar
 227 to the beam deflecting metasurface above. A representative
 228 SEM image of the fabricated GaN metasurface sample is
 229 shown in Fig. 3(b). The back focal plane measurements
 230 shown in Figs. 3(c) and 3(f) demonstrate the input light
 231 deflecting to the T_{-1} and T_{+1} orders for the p - and s -
 232 polarizations, respectively. The spectral dependence of the mea-
 233 sured diffraction orders, along with the corresponding
 234 numerical simulations, is shown in Figs. 3(d) and 3(g).
 235 Experimentally, we measure $\sim 50\%$ of the transmitted light
 236 channeled into the T_{-1} order for the p -polarized light and
 237 $\sim 40\%$ into the T_{+1} order for the s -polarized light. The rela-
 238 tive diffraction efficiencies achieved in our experiments are
 239 $\sim 74\%$ for the p -polarized light and $\sim 66\%$ for the s -polarized
 240 light [Figs. 3(e) and 3(h)]. The experimentally realized
 241 extinction ratios are 8.6/1 and 6.2/1 for the p - and s -polariza-
 242 tions, respectively.

243 In conclusion, we experimentally demonstrate GaN as
 244 a suitable material platform for realizing a wide range of

high-efficiency metasurface-based devices with enhanced 245
 functionalities operating through the whole visible spec- 246
 trum including the deep blue spectral region around 247
 450 nm. As a proof-of-concept demonstration, we have 248
 experimentally showed an epitaxially grown GaN based 249
 polarization insensitive metasurface that diffracts incom- 250
 ing light at 460 nm wavelength to an angle of 20° with 251
 $\sim 70\%$ absolute transmission efficiency and $\sim 90\%$ relative 252
 transmission efficiency. These reasonably high efficiencies 253
 are achieved despite the fact that the refractive index 254
 of the metasurface is the same as the underlying substrate, 255
 which is widely believed to lower the efficiency. 256
 Additionally, we have also demonstrated a polarization 257
 beam splitter working at 430 nm wavelength and capable 258
 of separating the p - and s -polarizations with the relative 259
 efficiencies of 73% and 67%, respectively. The corre- 260
 sponding extinction ratios of 8.6/1 and 6.2/1 for the p - and 261
 s - polarizations, respectively, were obtained. We expect 262
 that further development of metasurfaces based on GaN 263
 and its alloys with InN and AlN will pave the way for 264
 active, nonlinear, and quantum nanophotonics compatible 265
 with the emission wavelengths of atomic quantum emitters 266
 such as Ca^+ and Sr^+ ions.³⁹ 267
 268

See [supplementary material](#) for a complete description 269
 of the nanofabrication and optical characterization methods 270
 and design of the polarizing beam splitter. 271

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